



OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)		
X		Yao et al., "Single Crystal Silicon Supported Thin Film Micro Mirrors for Optical Applications" Opt. Eng. 36(5) 1408-1413 (May 1997)
Y		Conant et al. "A Flat High Frequency Scanning Micromirror" Abstract Submitted to Hilton Head 2000
Z		Storment et al. "Flexible Dry Release Process for Aluminum Electrostatic Actuators" Journal of Microelectromechanical Systems Vol. 3 No. 3 Sept 1994
AA		Mits et al., "An Out-of-Plane Polysilicon Actuator With a Smooth Vertical Mirror for Optical Fiber Switch Application"
AB		Marxer et al. "Vertical Mirrors Fabricated by Deep Reactive Ion Etching For Fiber-Optic Switching Applications" Journal of Microelectromechanical Systems, Vol. 6 No. 3, Sept 1997
AC		Fedder, G.K., "integrated microelectromechanical systems in conventional CMOS", Proceedings of 1997 IEEE International Symposium on Circuits and Systems. Circuits and Systems in the Information Age. ISCAS '97 (Cat. No. 97CH35987), pages 2821-2824, vol. 4
EXAMINER <i>Robert C. Best</i>		DATE CONSIDERED <i>10/27/02</i>
* EXAMINER: Initial if reference considered, whether or not citation is in conformance with MFEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.		